

## Effect of Doping with Cobber on Optical Properties of Zinc Oxide Thin Films Prepared by Sol-Gel Method

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### Abstract:

Thin films of cobber doped ZnO have been prepared on glass substrate using the Sol-Gel spin coating technique. The effect of doping percentage of Cu to ZnO thin films on the optical properties and optical constants are concluded from absorption and transmission measurements, which are obtained by using double beam UV-Visible 1800 spectrophotometer in the wavelength (300-800)nm. It was found that the transmittance increases with increasing the doping percentage (0.01, 0.02, 0.03 and 0.04)mol%, while the Absorbance is decreased. The optical energy band gaps have been evaluated and their values seem to be decreased by increasing the doping concentration level in the range(0.01, 0.02, 0.03)mol% followed by a rise with increasing the doping level to 0.04mol%.

**Keywords:** Sol-Gel, semiconductor, doping, optical energy band gap, optical properties

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### Introduction

The research concentrated on ZnO semiconductor material for many decades, due to its convenient properties and prospects in optoelectronic applications. The availability of high-quality ZnO thin film and a large exciton binding energy (60meV), besides its simple crystal-growth technology<sup>[1]</sup>, has made it one of the most candidates for many applications.

Although research focusing on ZnO goes back many decades, it gained more interest after recent work has predicted that ZnO-based semiconductors can present ferromagnetic behavior besides p-type conduction at room temperature when doped with transition metals such as Mn<sup>[2,3]</sup>. In addition, by controlling the doping level electrical properties can be changed from insulator through n-type semiconductor to metal while maintaining optical transparency that makes it useful for transparent electrodes in flat-panel displays and solar cells. There have been a number of publications which appear to confirm these predictions<sup>[1]</sup>.

Applied ZnO materials should be stable in hostile environment containing acidic and alkali solutions, oxidizing and reducing atmospheres and elevated temperature. These properties are strongly related to the methods of elaboration. High quality ZnO thin films can be grown at relatively low temperature less than 700°C<sup>[1]</sup>, by a number of methods including: pulsed laser deposition, dc reactive magnetron sputtering, atomic layer deposition, sol-gel spin coating, RF magnetron sputtering, metal organic chemical vapor deposition and chemical spray pyrolysis<sup>[4-8]</sup>. Among these methods, the Sol-Gel method with spin coating technique has been applied in this work.

This study is focused on the growth of cobber doped ZnO thin films of different doping concentration levels deposited on glass substrate by sol-gel process spin coating. In addition, studying Cu doping concentration level on the optical properties.

### Material and Methods

#### Samples preparation:

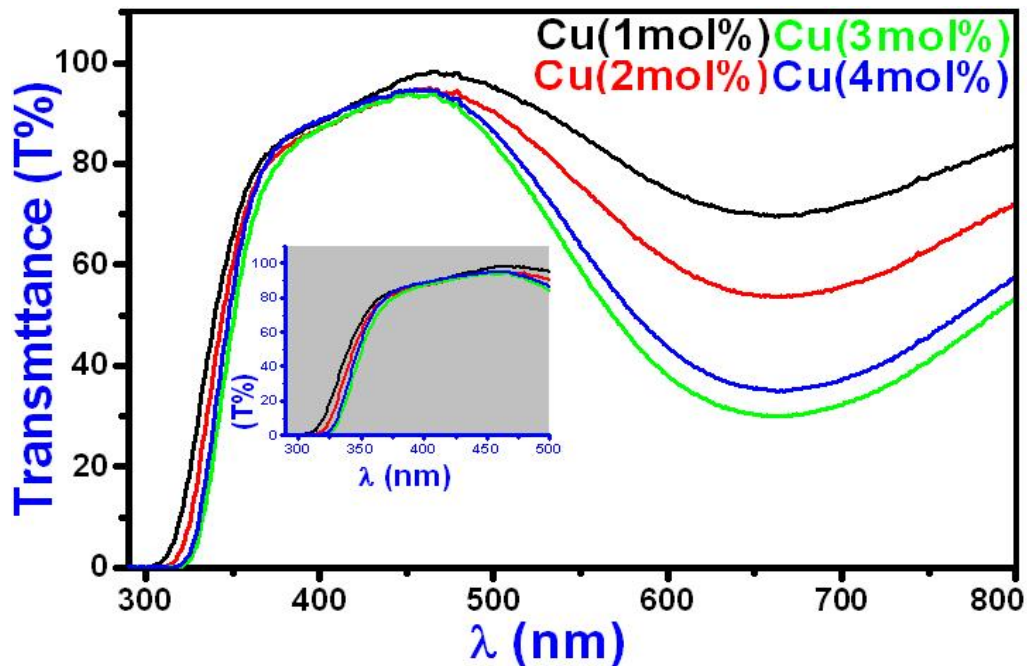
Cobber doped ZnO thin films were fabricated using the Sol-Gel spin coating technique. The initial stock solution was prepared from Zinc Acetate Dehydrate Zn(CH<sub>3</sub>COO)<sub>2</sub>·2H<sub>2</sub>O of purity 99.5% and Isopropanol CH<sub>3</sub>CH(OH)CH<sub>3</sub>, at 0.1 M concentration at room temperature. The solution was stirred on a magnetic stirrer with a hot plate for an hour. Some drops of Dietha-



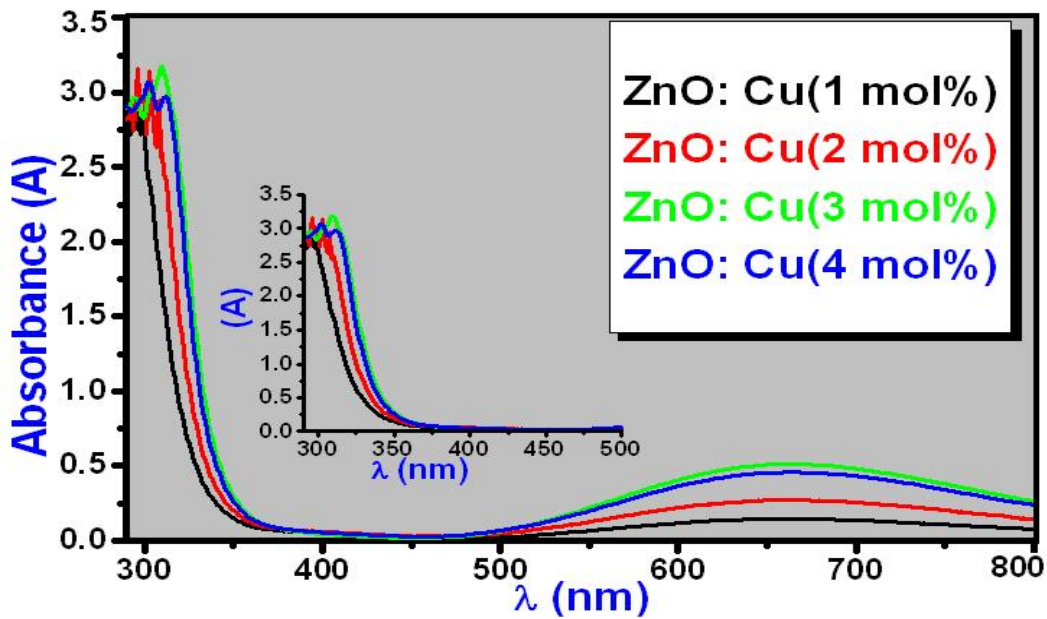
nol amine (DEA)  $C_2H_5-OH$  were added drop by drop to obtain a clear transparent solution with continues rotating for two hours. The doping was achieved by adding cobber nitrate  $Cu(NO_3)_2$ . The growth was performed with a slow spray rate on a circular well cleaned glass substrate of 10mm diameter and 1mm thickness. The thickness of the obtained films was measured by the Gravimetric method of about  $(300 \pm 20)$  nm. The optical properties of ZnO films were carried out with a double beam UV-Visible 1800 spectrophotometer.

## RESULTS AND DISCUSSION

The prepared samples have been loaded into the spectrophotometer, the transmittance and absorbance spectra have been collected. Figures (1) and (2) are showing changes in transmittance and absorbance spectrums of doped ZnO:Cu thin films of different doping concentration levels (0.1,0.2,0.3,0.4)mol%, as a function of photon wavelength. Figure(1) indicates that; in the visible light range(290-500)nm, all ZnO:Cu thin films show high transmittance exceeds 95% and a reduction in transmittance with increasing doping level. This behavior appears more clearly in the range(450-800)nm.



**Figure(1)** The transmittance of the deposited ZnO:Cu thin film versus wavelength for different doping concentration levels.

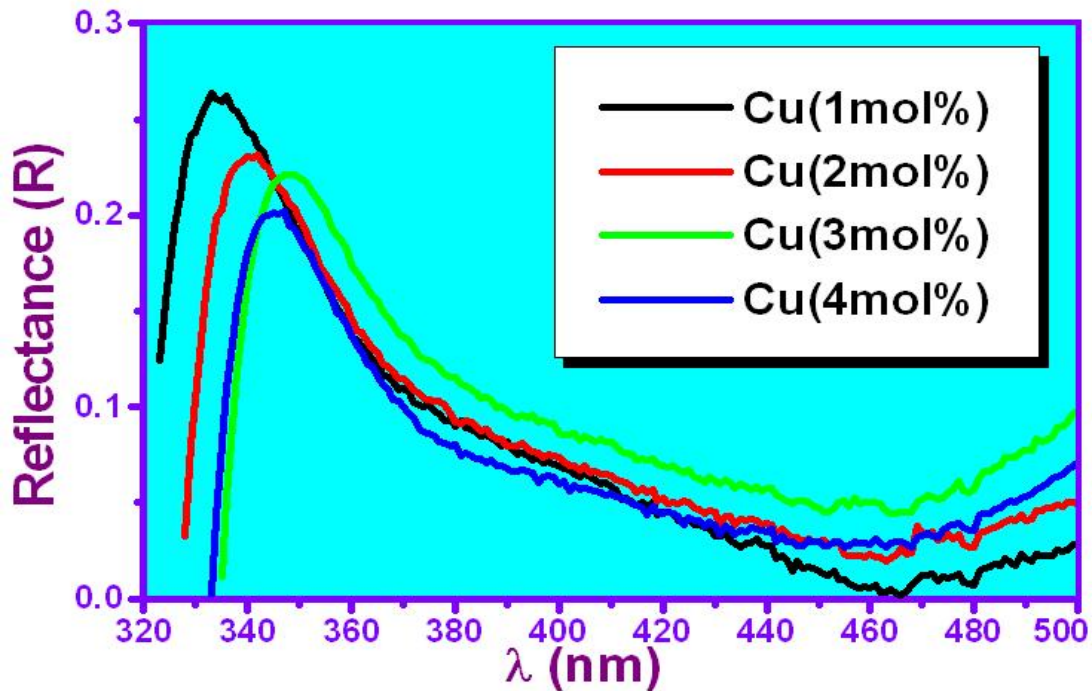


**Figure (2)** The absorbance spectrum of the deposited ZnO:Cu thin film versus wavelength for different doping concentration levels.

However, figure(2) indicates absorbance increase with rising doping percentage. These interesting changes can be attributed to enrolling of Cu atoms in the ZnO structure and may point to an increase in the localized impurity levels in the energy band gap of ZnO as the concentration of Cu is raised, the same behavior was also observed by Choi and Kim [9] and Bacaksizet al. [10].

Although the doping increase causes rise in absorbance, the highest value observed at doping level of 0.3mol%. In addition, the lowest transmittance noticed of the same film, which means that there is an irregular behavior obtained with increasing doping concentration level to 0.4mol%. This behavior can be explained according to Burstien -Moss effect[11].

The reflectance as a function of the wavelength has been calculated. The obtained spectrum is shown in figure(3). It shows a reduction in the reflectance with increasing the photon wavelength. The maximum reflectance can be observed at low wavelengths which equivalent to fundamental absorption edge. In addition, reflectance decreases with increasing Cu doping concentration level and a clear shift of the fundamental absorption edge to lower energy can be observed with rising concentration level of Cu(0.1, 0.2, 0.3)mol%. However, this behavior is inverted by increasing doping level to 0.4mol%.



**Figure(3)** Reflectance versus wavelength of the incident photon for different doping concentration level of Cu.

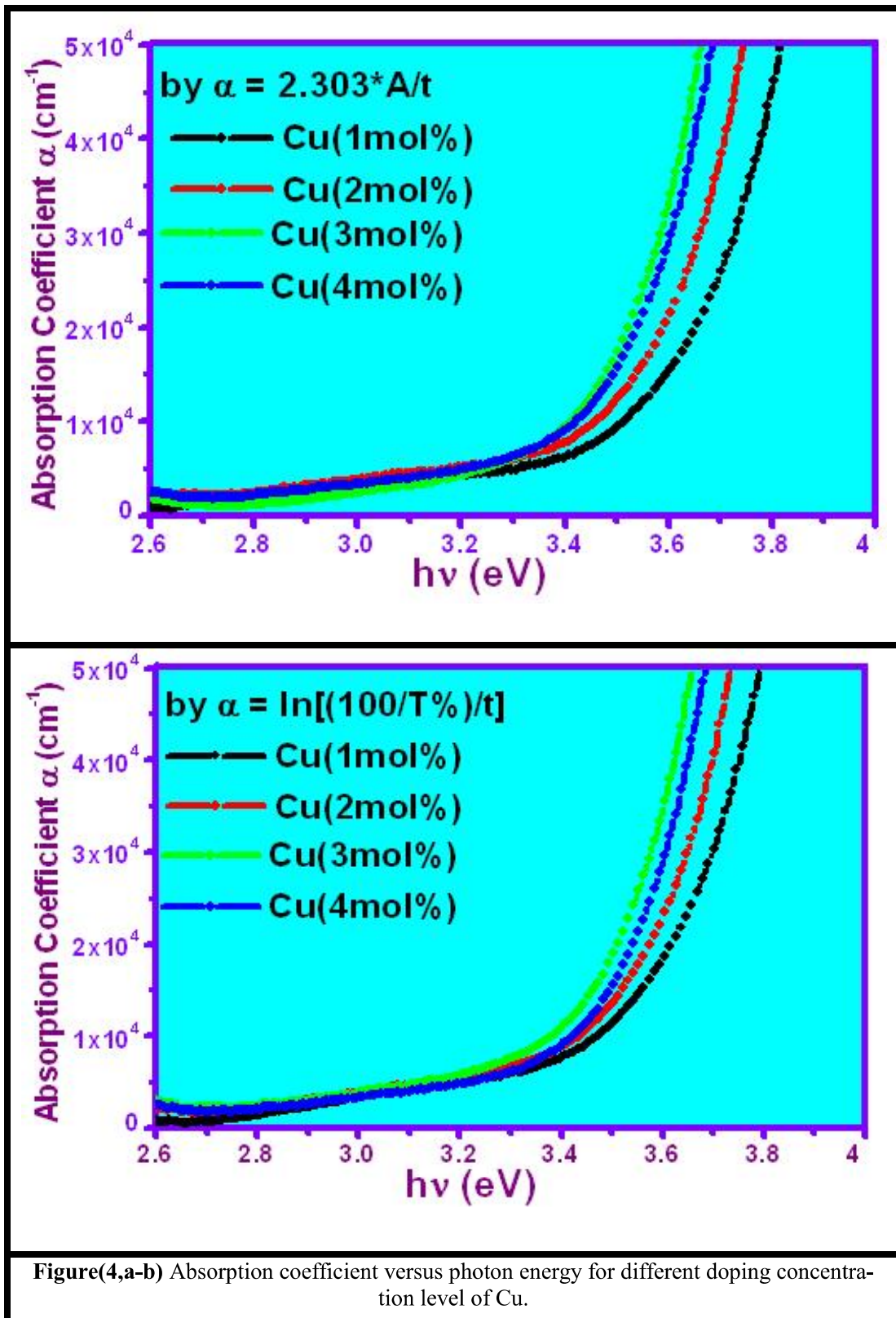
The absorption coefficient has been calculated using the relation  $[\alpha = 2.303A/t]$  and Bouger-Lambert law  $[\alpha = \ln(100/T\%)/t]$ . Absorption coefficient spectrum as a function of photon energy is indicated in figure(4(a,b)). The spectra are showing a slight rise of  $\alpha$  with increasing photon energy up to 3.1eV followed by an exponential increase of  $\alpha$  with increasing photon energy which is called Urbach tail. The spectral dependence of the absorption coefficient ( $\alpha$ ) and photon energy ( $h\nu$ ) is known as Urbach empirical rule, which is given by the following equation:  $[\alpha = \alpha_0 e^{\frac{h\nu}{E_u}}]$ , where  $\alpha_0$  is a constant and  $E_u$  denotes the energy of the band tail Urbach energy.

It can be seen from figure (4) that the film of 3mol% has the highest absorption coefficient.

The fundamental absorption edge, which corresponds to the electron excitation from valence band top to conduction band bottom is usually used to determine the value of direct optical band gap using the Tauc relationship [11];  $(\alpha h\nu)^2 = A [h\nu - E_g]$

Where A is a constant which is inversely proportional to amorphousity. Figure(5) shows the plot of  $(\alpha h\nu)^2$  versus photon energy of the films under investigation.

The calculated optical energy band gap values of doped ZnO:Cu thin films are showing in figure(4) and table(1). They indicate that increasing Cu doping concentration level (0.1, 0.2, 0.3)mol% leads to a reduction in the optical energy band gap which can be explained due to

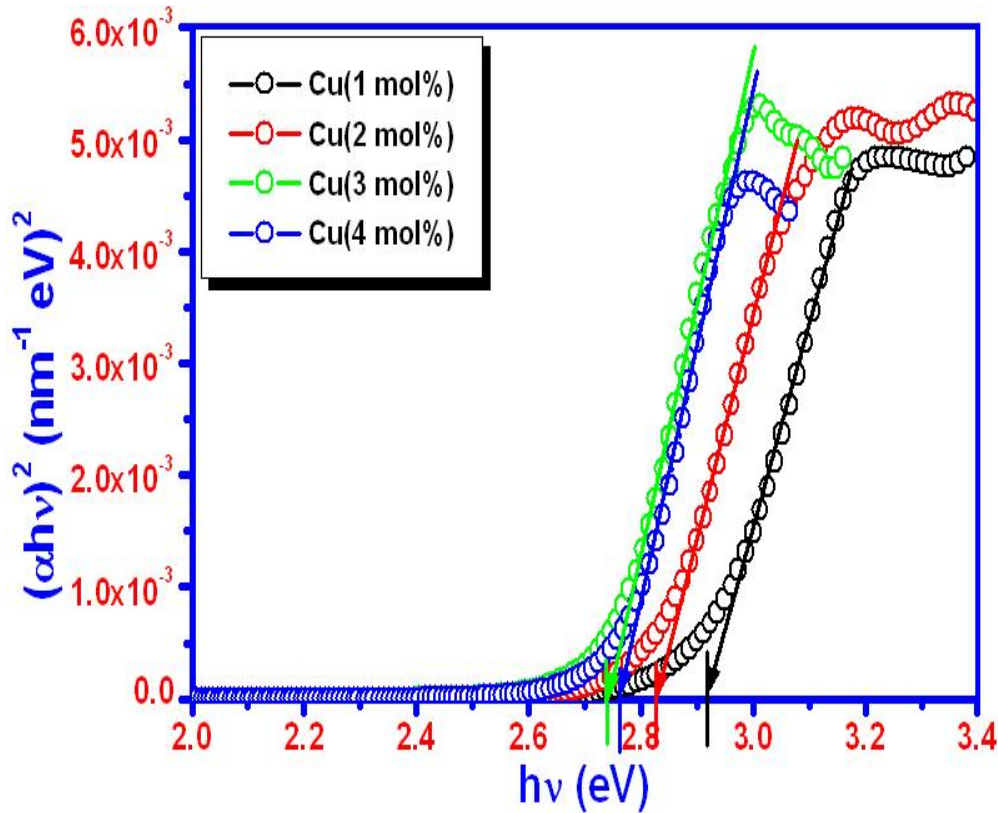


Figure(4,a-b) Absorption coefficient versus photon energy for different doping concentration level of Cu.

inserting localized energy states below conduction band. These states can be occupied by moving electrons from valence band. However, further increase in the Cu to 0.4mol% results in aslight rise in the optical energy band gapand this variation could be attributed to Burstein-



Moss shift[11,12]. Whereby, conduction band bottom is filled with electrons of donor atoms at room temperature. Therefore, moving electrons from valence band require a slight higher energy to be settled in the conduction band.



**Figure(5)** Dependence of  $(\alpha h\nu)^2$  on the photon energy of doped ZnO:Cu thin films.

According to the evaluated values of optical energy band gap, it is obvious that the film of 3mol% has the lowest energy band gap. Therefore, the highest absorption coefficient of this film which is shown in figure(4) can be explained.

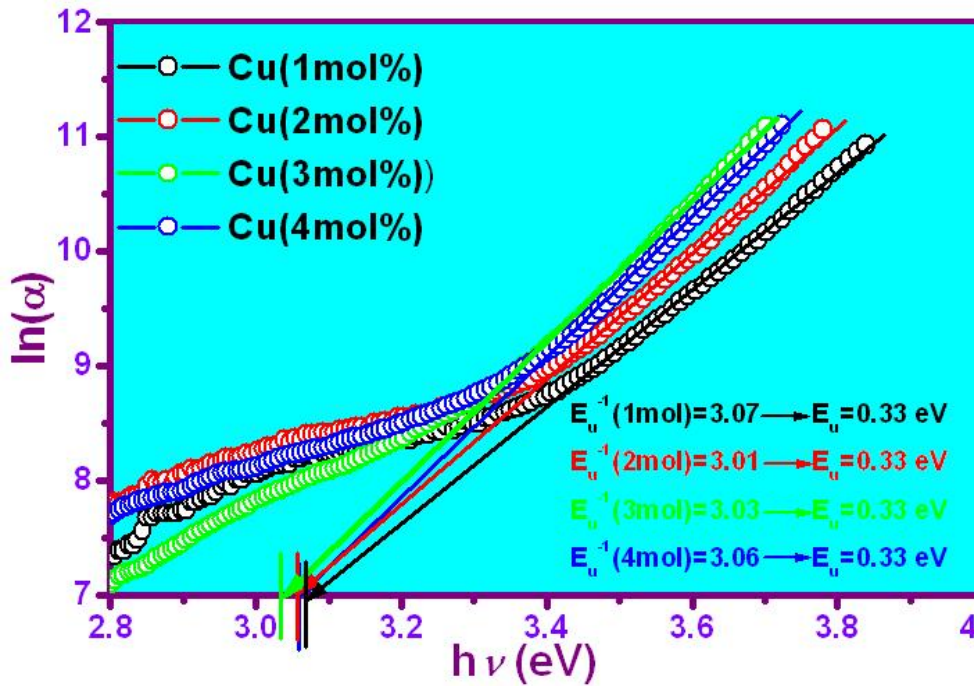
**Table(1)** Evaluated optical energy band gap of different concentration levels ZnO:Cu thin films.

Cu doping level	1mol%	2mol%	3mol%	4mol%
Optical energy gap $E_g$ (eV)	2.92	2.83	2.74	2.76

Urbach energy is one of the important parameters in thin films which indicates the degree of crystalline in the structure( amorphous or disorder) due to the formation of localized states with energies at the boundaries of the energy band gap.

According to the equation  $\ln \alpha = \ln \alpha_0 + \left(\frac{h\nu}{E_u}\right)$ , the Urbach energy can be obtained from the slope of the straight line of plotting  $\ln(\alpha)$  against the incident photon energy.

As shown in figure(6) Urbach energy values of doped ZnO thin films of different concentration levels of Cu are almost having the same value  $E_u \sim 0.33$ eV.

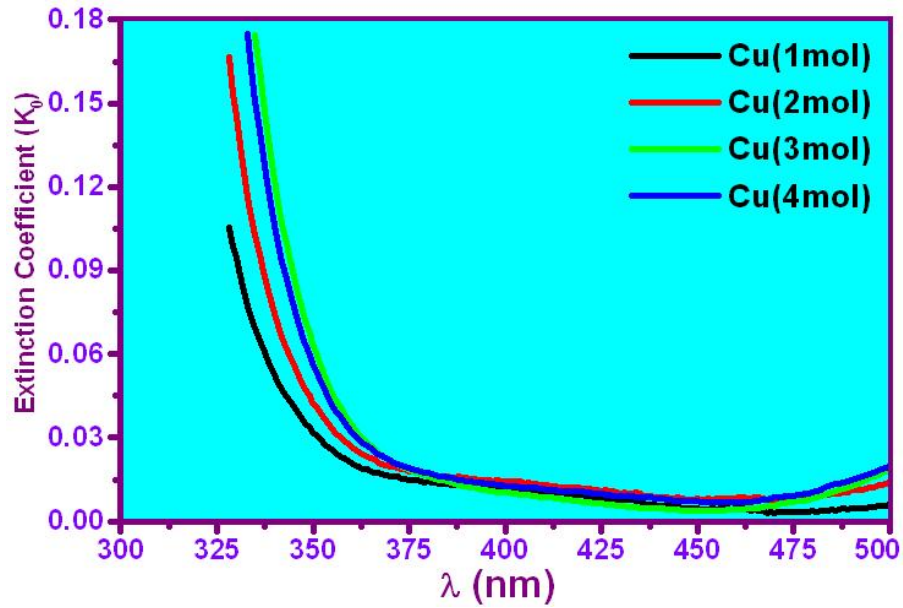


**Figure(6)** Urbach energy versus photon energy for different doping concentration level of Cu.

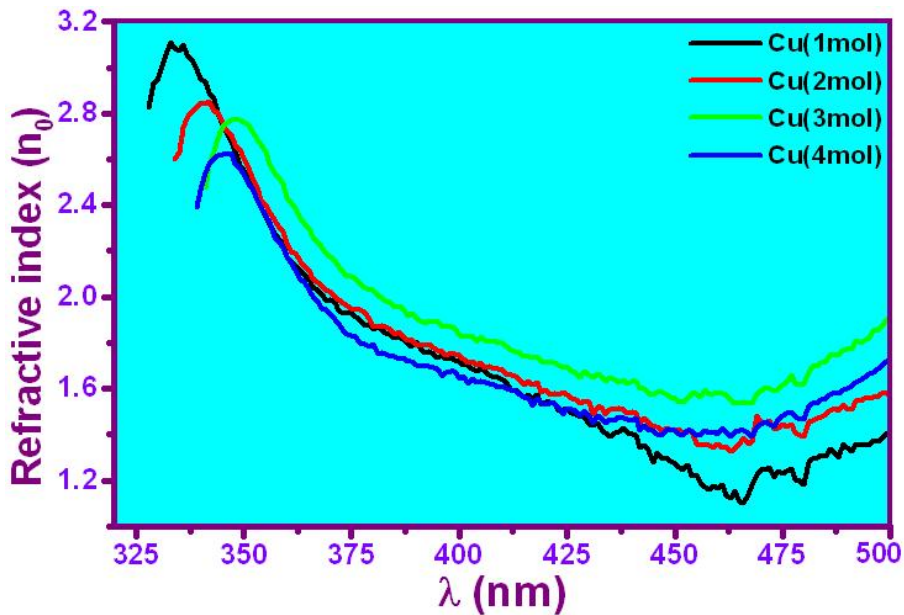
The extinction coefficient ( $K_0$ ) (the imaginary part of the refractive index<sub>[14]</sub>) of the thin films has been calculated by the relation<sub>[13]</sub>:  $K_0 = \frac{\alpha\lambda}{4\pi}$ . Figure(7) displays the extinction coefficient as a function of wavelength for whole Cu doped ZnO thin films. The extinction coefficient of whole samples have a peak at low  $\lambda$ , which decrease with increasing wavelength. In addition, the maximum values of  $K_0$  are obtained by the film of 3mol%, which is having the narrowest energy band gap.

Refractive index ( $n_0$ ) has been calculated by using the equation<sub>[13]</sub>;

$$n_0 = \left[ \left( \frac{1+R}{1-R} \right)^2 - (K_0^2 + 1) \right]^{1/2} + \frac{1+R}{1-R}$$
 Figure(8) represents refractive index variations as a function of wavelength of doped ZnO:Cu thin films of different concentration levels. It can be noticed that  $n_0$  is having a peak at low wavelength and decreases with rising  $\lambda$  and  $n_0$  curve is similar to the reflectance curve.



**Figure(7)** Extinction coefficient as a function of wavelength for Cu doped ZnO of different concentration levels.



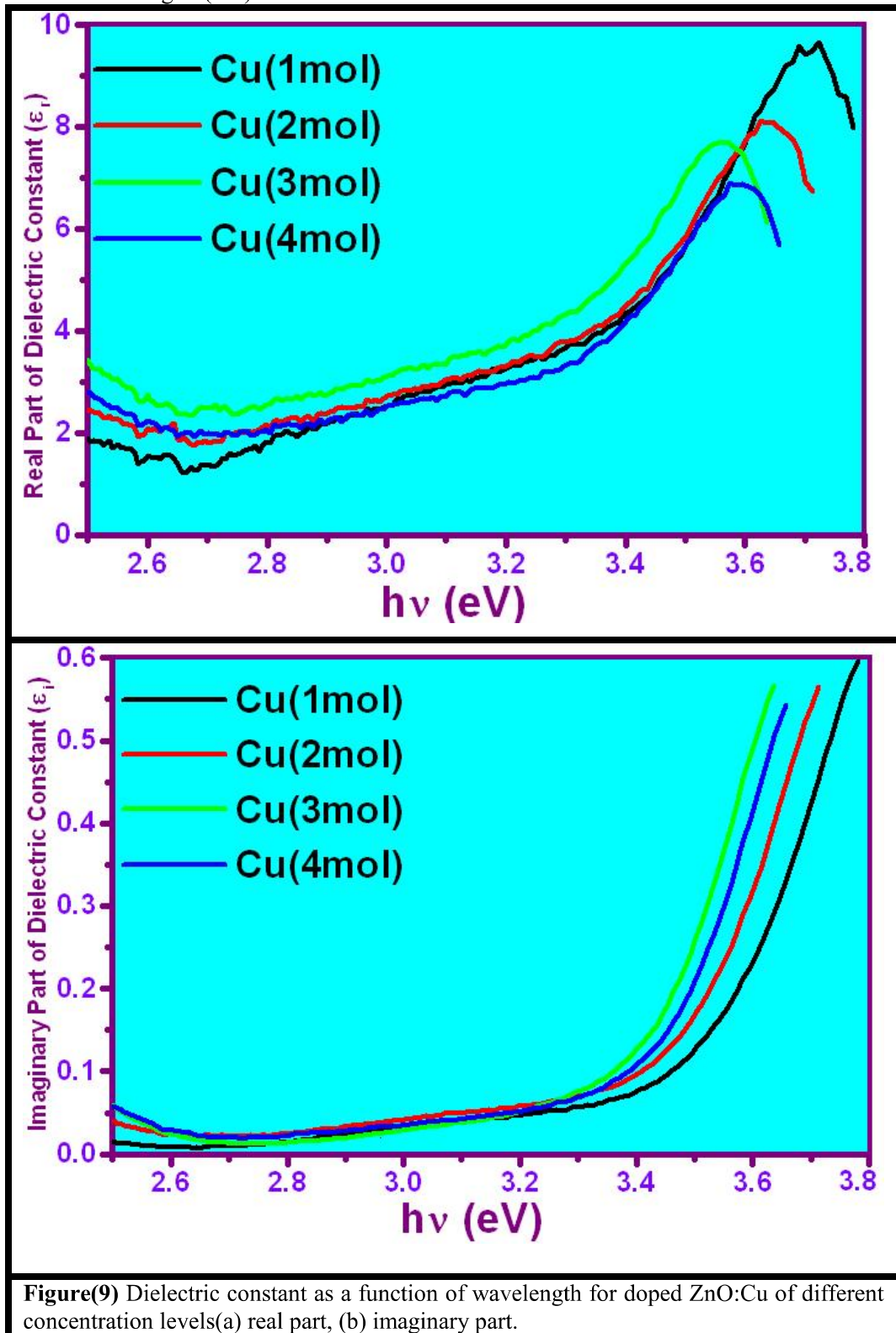
**Figure(8)** Refractive index as a function of wavelength for doped ZnO:Cu of different concentration levels.

Photon interaction with material may cause charge polarization. The polarization is normally described by the complex dielectric constant ( $\epsilon$ ), where  $\epsilon = \epsilon_r + \epsilon_i$ . Both the real part ( $\epsilon_r$ ) and imaginary part ( $\epsilon_i$ ) have been calculated according to the following equations respectively;  $\epsilon_r = n_0^2 - K_0^2$ ,  $\epsilon_i = 2n_0K_0$ , for every concentration level. Whereas,  $\epsilon_r$  represents the measure of polarizability and  $\epsilon_i$  represents the value of the loss energy due to the movement of polarized dipoles as heat.

Figures(9-a,b) show changes in the real part and imaginary part values of the dielectric constant as a function of photon energy for Cu-doped thin films of different concentration levels. Whereas both  $\epsilon_r$  and  $\epsilon_i$  of the prepared thin films increase with rising  $h\nu$ . In addition, Figure(9-a) shows that the doped thin film polarizability is decreased with increasing doping concentration level. Whereby, the lowest concentration level thin film has the highest polarizability.



On the other hand, this film is losing the minimum energy as a heat compared with other films as shown in figure(9-b).





### Conclusion:

Doped ZnO:Cu thin films of different percentages have been prepared by Sol-Gel spin coating technique. The analysis of UV-visible spectra have shown that the transmission of the Cu doped films were very high and exceeds 95% in the wavelength range (350-500)nm. Increasing doping level leads to a reduction in transmittance. On the other, it causes a rise in absorbance. In addition, it causes a shift of the fundamental absorption edge to higher wavelength values. As a result a reduction in optical energy band gaps is observed. The results show that all the deposited thin films have direct optical energy band gaps lying in the range of (2.74-2.94)eV. In addition, data obtained from absorption and transmittance spectra are used to determine some other optical parameters.

### REFERENCES

- 1) Özgür, Ü; Alivov, Ya, I; Liu, C; Teke, A; Reshchikov, M. A; Doğan, S. C; Avrutin, V; Cho S. J; and Morkoçd, H; Appl. Phys. Lett. 2005, **V(98)**, 041301 ,
- 2) Pcarton, S. J; Heo, W. H; Ivil, M; Norton, D. P; and Steiner, T; Semicon. Sci. technol. 2004, **V(19)**, R59.
- 3) Ueda, K; Tabata, H ;and Kawai, T; Appl. Phys. Lett., 2001, **V(79)**, 988.
- 4) Lin, J. M; Zhang, Y. Z; Ye, Z. Z; Gu, X. Q; Pan, X. H; Yang, Y. F; Lu, J. G; He H. P; and Zhao, B. H; Applied Surface Science, 2009, **V(255)**, 6460.
- 5) Hong, R; Huang, J; He, H; Fan, Z; and Shao, J; Applied Surface Science, 2005, **V(242)**, 346.
- 6) Lim, J; and Lee, C; Journal of Alloys And Compounds, 2008, **V(449)**, 371.
- 7) Srinivasan, G; Rajendra Kumar, R. T; and Kumar, J; Optical Materials, 2007, **V(30)**, 314.
- 8) Huang, B; Li, J; Wu, Y; Guo, D; and Wu, S; Materials Letters, 2008, **V(62)**, 1316.
- 9) Choi, C. H; and Kim, S. H; Thin Solid Films, 2007, **V(515)**, 2864.
- 10) Bacaksiz, E; Aksu, S; Basol, B. M; Altunbas, M; Parlak, M; and Yanmaz, E; Thin Solid Films, 2008, **V(516)**, 7899.
- 11) Sharma, M; and Mehra, R. M; Applied Surface Science, 2008, **V(255)**, 2572.
- 12) Hudait, M. K; Modak, P; and Krupanidhi, S. B; Materials Science and Engineering, 1999, **V(56)**, pp.1-11
- 13) Molt, N; and Davis, E; Electronic process in Non-Crystalline Materials, 2<sup>nd</sup> edition, 1971, University Press, Oxford
- 14) Mahasin, F; Al-Kadhemy, H; and Khaleel, R; Advances in Physics Theories and Applications, 2013, **V(24)**, pp.57-68